



**COPY OF PAPERS  
ORIGINALLY FILED**

#16/Arnold C  
Atrial  
6/16/02

Attorney Docket SEL 171

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of:

Kadono et al.

Serial No.: 09/535,233

Filed: March 24, 2000

For: A Method Of Manufacturing A  
Semiconductor Device

Art Unit: 2823

Examiner: W. Coleman

Commissioner for Patents  
Washington, D.C. 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

Commissioner for Patents  
Washington, D.C. 20231

on May 26, 2002

Rachelle Hamerquist

Rachelle Hamerquist 5/26/02

Signature

TECHNOLOGY CENTER 2800

RECEIVED

JUN 11 2002

Sir:

In response to the Final Rejection dated March 26, 2002, a RCE being submitted herewith,  
please amend the above-identified application as follows:

**IN THE CLAIMS:**

Please amend the claims as follows:

11. (Amended) A method of manufacturing a semiconductor device, comprising steps of:

forming a semiconductor film formed over a substrate;

spinning the substrate;

contacting an etching solution to a surface of said semiconductor film and scattering the  
etching solution during said spinning, thereby contaminating impurities are removed from the surface;  
and then